



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of: **Masayuki FURUHASHI et al.**

Group Art Unit: **2813**

Application Number: **10/696,775**

Examiner: **Stephen W. Smoot**

Filed: **October 30, 2003**

Confirmation Number: **7971**

For: **METHOD FOR FABRICATING A SEMICONDUCTOR DEVICE
INCLUDING THE USE OF A COMPOUND CONTAINING
SILICON AND NITROGEN TO FORM AN INSULATION FILM
OF SiN, SiCN OR SiOCN**

Attorney Docket Number: **032076**

Customer Number: **38834**

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

July 18, 2006

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated January 19, 2006 for three month(s) from April 19, 2006 to July 19, 2006.

Attached please find a check in the amount of \$1,020.00 for the cost of the extension.

If any additional fees are due in connection with this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,

WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP

Kenneth H. Salen

Attorney for Applicants

Registration No. 43,077

Telephone: (202) 822-1100

Facsimile: (202) 822-1111

07/20/2006 CNGUYEN2 00000021 10696775

03 FC:1253

1020.00 0P

KHS/rf